

An Ultra Broadband GaAs MESFET Preamplifier IC for a 10 Gb/s Optical Communication System

Miyo Miyashita, Kosei Maemura, Kazuya Yamamoto, Teruyuki Shimura, Masamichi Nogami, Kuniaki Motoshima, Tadayoshi Kitayama, and Yasuo Mitsui

Abstract—An ultra broadband GaAs MESFET preamplifier IC has been developed for a 10 Gb/s optical communication system. High transimpedance of 44 dBΩ has been obtained over dc to 12 GHz. A receiver has also been fabricated by using this preamplifier IC and a photodiode. The receiver operates with extremely low equivalent input noise current of 12.6 pA/√Hz over dc to 7.8 GHz. This paper describes circuit design and high frequency characteristics of both the preamplifier IC and the receiver.

INTRODUCTION

A HIGH SPEED and broadband optical communication system useful not only for telecommunication but also for large capacity data and image transmission has increasingly been demanded in realizing the next generation of Broadband Integrated Services Digital Network (B-ISDN). Up to now, a 2.4 Gb/s system has almost come up to practical use and a system with transmission rate of up to 10 Gb/s or more has extensively been studied [1]–[3].

In the fiber optic link, a conventional optical receiver consists of three functional blocks which are equalization, retiming, and regeneration. A preamplifier is a key component in the equalization block and requires low noise and broadband characteristics. Since a preamplifier IC is used with a photodiode in a receiver, the IC has to be designed with consideration of the photodiode's parameters, especially its parasitic capacitance [4].

This paper describes both the circuit design and high frequency characteristics, and superior production controllability in the fabrication process for the preamplifier IC.

CIRCUIT DESIGN

Fig. 1 shows the circuit diagram of the IC. Noise sources in a receiver composed of the IC and a p-i-n-photodiode include thermal noises of the FET and feedback resistor, shot noise due to both the dark current of the p-i-n photodiode and gate leakage current of the FET, and 1/f noise.

The dominant noise sources in a receiver are the ther-

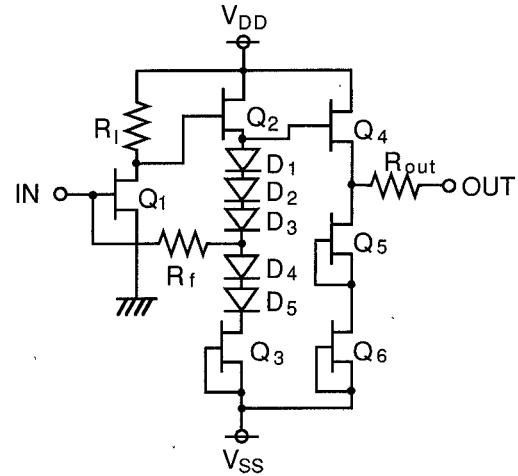


Fig. 1. Circuit diagram of the IC.

mal noises in the input FET and the feedback resistor. These thermal noises depend on total input capacitance of a receiver or feedback resistance. Taking into account the trade-off between noise performance and broad bandwidth, the IC has to be designed so as to get high feedback resistance and low total input capacitance simultaneously.

The equivalent input noise ($\overline{in_{FET}^2}$) due to thermal noise in the input FET(Q_1) is described by the following equation [5],

$$\overline{in_{FET}^2} = 4kT\Gamma \frac{(\omega \cdot C_t)^2}{g_m} \Delta f. \quad (1)$$

where k is Boltzmann's constant, T is absolute temperature, ω is angular frequency, and g_m is transconductance of the input FET(Q_1). C_t is equal to the sum of the input gate capacitance (C_g) of the input FET and parasitic capacitance (C_{PD}) of the photodiode. Γ is a noise term [5] denoted as follows:

$$\Gamma = P - 2Q \left(\frac{C_g}{C_t} \right) + R \left(\frac{C_g}{C_t} \right)^2 \quad (2)$$

where P , Q , and R are factors depending on various FET parameters and gate bias [5]–[7]. Input noise in the input FET is expressed in (3) where g_{mu} and C_{gu} are transconductance and input gate capacitance per unit gate width.

$$\overline{in_{FET}^2}(W) = 4kT\Gamma(W) \frac{(\omega(C_{PD} + C_{gu} \cdot W))^2}{g_{mu} \cdot W} \Delta f \quad (3)$$

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and

$$\begin{aligned} \Gamma(W) &= P - 2Q \left(\frac{C_{gu} \cdot W}{C_{PD} + C_{gu} \cdot W} \right) \\ &\quad + R \left(\frac{C_{gu} \cdot W}{C_{PD} + C_{gu} \cdot W} \right)^2 \end{aligned} \quad (4)$$

where W is gate width of the FET(Q_1). In (3), noise current ($\overline{in_{FET}^2}$) is minimized at a condition of

$$W = \sqrt{\frac{P}{P - 2Q + R}} \cdot \frac{C_{PD}}{C_{gu}} \simeq 0.7 \cdot \frac{C_{PD}}{C_{gu}} \quad (5)$$

where each parameter P , Q , and R for the FET with gate length of $0.5 \mu\text{m}$ is estimated from a previous report [5] to be 1.105, -0.436 , and 0.303 , respectively.

On the other hand, the thermal noise of the feedback resistor ($\overline{in_{R_f}^2}$) is expressed by the following equation [8], [9],

$$\begin{aligned} \overline{in_{R_f}^2} &= \frac{4kT}{R_f} \Delta f \\ &= \frac{4kT \cdot 2\pi f_{3\text{dB}} (C_{PD} + C_{gu} \cdot W)}{A} \Delta f \end{aligned} \quad (6)$$

where R_f is the feedback resistance, and A is open loop gain. $f_{3\text{dB}}$ is the bandwidth of a receiver consisting of a preamplifier and a photodiode, which is expressed by

$$f_{3\text{dB}} = \frac{A}{2\pi R_f (C_{PD} + C_{gu} \cdot W)}. \quad (7)$$

In Fig. 2(a) and (b), two kinds of equivalent input noises ($\overline{in_{FET}^2}$ and $\overline{in_{R_f}^2}$) and total input noise current ($\sqrt{\overline{in_t^2}}$) are plotted against gate width (W), which are obtained by integrating (3) and (6) with respect to frequency from 0 to $f_{3\text{dB}}$. Equivalent total input noise ($\sqrt{\overline{in_t^2}}$) is shown as follows:

$$\begin{aligned} \sqrt{\overline{in_t^2}} &= \left(\left(\int_0^{f_{3\text{dB}}} (\overline{in_{R_f}^2} + \overline{in_{FET}^2}) df \right) / f_{3\text{dB}} \right)^{1/2} \\ &= \left(\frac{4kT \cdot 2\pi f_{3\text{dB}} (C_{PD} + C_{gu} \cdot W)}{A} \right. \\ &\quad \left. + \frac{4kT \cdot (2\pi)^2 f_{3\text{dB}}^2}{3} \right. \\ &\quad \left. \times \left(\frac{P \cdot C_{PD}^2}{g_{mu} \cdot W} + \frac{(P - 2Q + R) \cdot C_{gu}^2 \cdot W}{g_{mu}} \right. \right. \\ &\quad \left. \left. + \frac{2(P - Q) \cdot C_{gu} \cdot C_{PD}}{g_{mu}} \right) \right)^{1/2} \end{aligned} \quad (8)$$

We selected the gate width of the input FET(Q_1) so as to get the minimum total input noise current ($\sqrt{\overline{in_t^2}}$), which

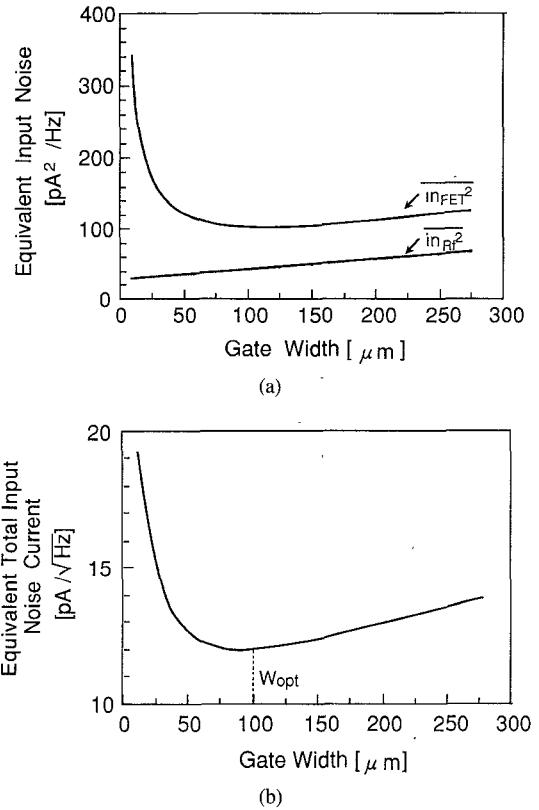


Fig. 2. (a) Two kinds of equivalent input noises ($\overline{in_{FET}^2}$ and $\overline{in_{R_f}^2}$) and (b) equivalent total input noise current ($\sqrt{\overline{in_t^2}}$) versus the gate width of FET(Q_1).

is realized at a condition of

$$W = \left(\frac{2\pi f_{3\text{dB}} \cdot P \cdot A}{2\pi f_{3\text{dB}} \cdot (P - 2Q + R) \cdot A + 3(g_{mu} / C_{gu})} \right)^{1/2} \cdot \left(\frac{C_{PD}}{C_{gu}} \right). \quad (9)$$

In Fig. 3, the 3 dB bandwidth ($f_{3\text{dB}}$) and equivalent input noise current ($\sqrt{\overline{in_{R_f}^2}}$) in the receiver are plotted against R_f obtained from SPICE with the GaAs MESFET model. The gate width of the input FET is $100 \mu\text{m}$. In the design, $f_{3\text{dB}}$ is chosen to be 7 GHz which is 70 percent of 10 Gb/s . In Fig. 3, $f_{3\text{dB}}$ of 7 GHz is obtained for R_f of 400Ω .

Shot noises due to the dark current in the p-i-n-photodiode ($\overline{in_d^2}$) and gate leakage current in the input FET ($\overline{in_g^2}$) are shown by the following equations [8], [9]:

$$\overline{in_d^2} = 2eI_d \Delta f \quad (10)$$

$$\overline{in_g^2} = 2eI_g \Delta f \quad (11)$$

where ‘‘e’’ is electron charge, I_d is dark current in the photodiode, and I_g is gate leakage current in the input FET(Q_1). Dark current in the InP p-i-n-photodiode is less than 100 nA and gate leakage noise in the input FET is an order of 0.1 to $1.0 \mu\text{A}$ for $100 \mu\text{m}$ gate width GaAs MESFET. Total shot noise is less than $0.5 \text{ pA}^2/\text{Hz}$ and negligibly small compared with thermal noise of R_f .

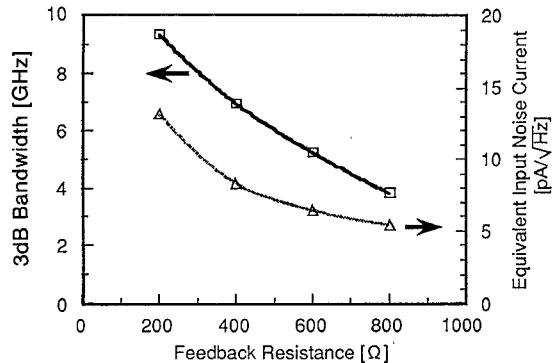


Fig. 3. 3-dB band-width and equivalent input noise current versus feedback resistance.

At the low frequency, $1/f$ noise ($\overline{\text{in}_1^2/f}$) is shown by the following equation,

$$\overline{\text{in}_1^2/f} = 4kT\Gamma \frac{(\omega \cdot C_l)^2}{g_m} \cdot \frac{f_c}{f} \Delta f \quad (12)$$

where f is frequency ($= \omega/2\pi$) and f_c is the $1/f$ noise

$$Z_{\text{trans}} = \frac{-R_f}{\left(\frac{j\omega C_g}{A} \right) \cdot \left(j\omega C_{PD} \cdot \left(R_g + \frac{1}{j\omega C_g} \right) \cdot R_f + R_f + \left(R_g + \frac{1}{j\omega C_g} \right) \right) + 1} \quad (13)$$

corner frequency of the FET [8]. Because f_c is approximately 50 MHz for GaAs MESFET [8], $1/f$ noise can be neglected compared with the thermal noise of the input FET.

Each component of the IC shown in Fig. 1 is optimized using SPICE simulation except the input FET(Q_1). Table I shows the size of FET and diode and resistance in the IC after optimization. In the IC, we use resistive load because it has smaller noise contribution at the IC input than active load [9]. The load resistance (R_1) is 500 Ω . For the transconductance (g_m) of input FET(Q_1) which is an order of 10 mS, thermal noise of load resistor (R_1) is neglected by setting $R_1 \gg 1/g_m$ [10].

In the output buffer, because dc bias is over +2.5 V at the output port and V_{SS} is -5 V, dc voltage over 7 V is supplied between the output port and V_{SS} . Considering a breakdown voltage of each FET to be around 7 V, the output buffer is constructed by adding level-shift FET(Q_5) between the output port and drain of the FET(Q_6). Output impedance of the source follower FET(Q_4) of 400 μm gate width is approximately 10 Ω . To prevent reflection at the output port, the output impedance is matched to 50 Ω by connecting a resistor R_{out} of 40 Ω to the output terminal.

Fig. 4 shows the microphotograph of the IC. To realize a low noise and broadband preamplifier IC, we adopted the Self-Aligned Gate MESFET (SAGFET). The SAGFET has been developed for high speed GaAs LSI's, such as SRAM's [11] and gate arrays [12]. Because of excellent process controllability, the SAGFET leads to uniform preamplifier performance. The SAGFET has a Buried P-layer Lightly Doped Drain structure (BPLDD) fabricated

TABLE I
EACH COMPONENT SIZE OF THE IC

| Element | Size |
|------------------|-------------------|
| Q_1 | 100 μm |
| Q_2 | 200 μm |
| Q_3 | 200 μm |
| Q_4 | 400 μm |
| Q_5 | 200 μm |
| Q_6 | 200 μm |
| $D_1 \sim D_5$ | 100 μm |
| R_f | 500 Ω |
| R_f | 400 Ω |
| R_{out} | 40 Ω |

by a 0.5 μm self-aligned WSi_x gate process [11]. Because a WSi gate has high sheet resistance compared with a conventional Au or Al gate, the effect of gate resistance on high frequency operation cannot be neglected and brings about degraded bandwidth and noise performance. Taking gate resistance into account the transimpedance and 3 dB bandwidth of the receiver are expressed as follows:

$$f_{3\text{dB}} \approx \frac{A}{2\pi ((C_{PD} + C_g) \cdot R_f + C_g \cdot R_g)} \quad (14)$$

respectively. Thermal noise in the gate resistance is expressed as

$$\overline{V_{R_g}^2} = 4kT R_g \Delta f \quad (15)$$

where R_g is gate resistance.

The effect of gate resistance can be neglected for the case that gate resistance is much smaller than the feedback resistance. Parallel connection of short gate fingers is effective to reduce the gate resistance of the FET. The distributed gate resistance (R_g) is expressed approximately [13] as follows:

$$R_g = R_{\square} \cdot \frac{W_u}{L_g \times N} \cdot \frac{1}{3} \quad (16)$$

where R_{\square} is the sheet resistance of WSi gate metal (about 4 Ω/\square), L_g is the gate length (0.5 μm), W_u is unit finger width, and N is the number of the fingers. Fig. 5 shows the measured and calculated R_g 's versus gate width of the SAGFET for $N = 2, 4$, and 8. For $N = 4$, low R_g of 17.6 Ω has been obtained for gate width of 100 μm , which agrees well with an estimated value from (16).

As concerns the other device parameters, transconductance (g_m) and drain conductance (g_d) are 300 mS/mm and 6 mS/mm with standard deviations of 30 mS/mm and 0.7 mS/mm over a 3 inch wafer, respectively. The threshold voltage (V_{th}) of the FET is -0.5 V and its standard deviation (σV_{th}) is 30 mV.

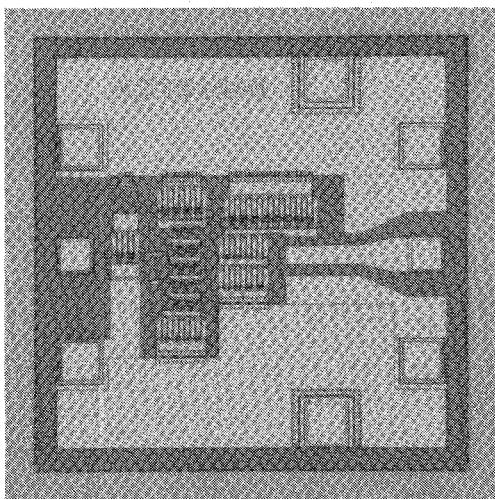


Fig. 4. Microphotograph of the preamplifier IC. (The chip size is $0.8 \text{ mm} \times 0.8 \text{ mm}$)

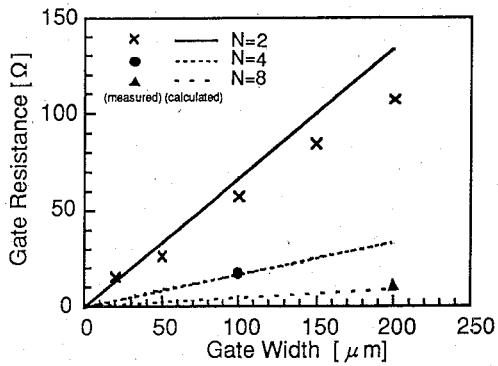


Fig. 5. Gate resistance (R_g) versus gate width of the SAGFET.

To simplify on-wafer RF measurements, a coplanar structure is employed for both input and output lines and two metal-insulator-metal capacitors are integrated as bypass capacitors for stabilizing the power supplies of +5 V and -5 V. The chip size is $0.8 \text{ mm} \times 0.8 \text{ mm}$.

CHARACTERISTICS

Fig. 6 shows the S -parameters of the IC. The high gain $|S_{21}|$ of 9 dB and the broad bandwidth over 10 GHz have been obtained. Good matching has also been achieved. $|S_{22}|$ is less than -10 dB for the whole frequency range.

Fig. 7 shows the transimpedance characteristics of the IC calculated by using S -parameters. The high Z_{trans} of 44 $\text{dB}\Omega$ and the excellent broad bandwidth ($f_{3\text{dB}}$) of 12 GHz have also been obtained. The measured results show good agreement with those of the simulation. Fig. 8 shows the distribution of Z_{trans} and $f_{3\text{dB}}$ for a 3 inch wafer. Each standard deviation, σZ_{trans} and $\sigma f_{3\text{dB}}$, is as small as 0.2 $\text{dB}\Omega$ and 0.2 GHz, respectively. The uniform preamplifier performance comes from our excellent process controllability.

Fig. 9 shows the frequency response of a receiver that consists of the IC and an InP p-i-n photodiode. The diameter of the photodiode is $30 \mu\text{m}^\phi$, dark current is 30 nA

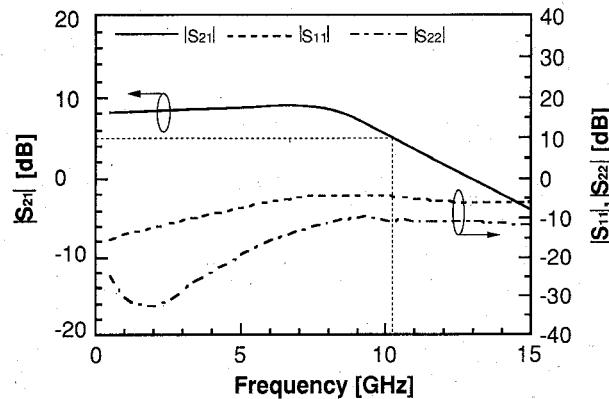


Fig. 6. S -parameters of the IC.

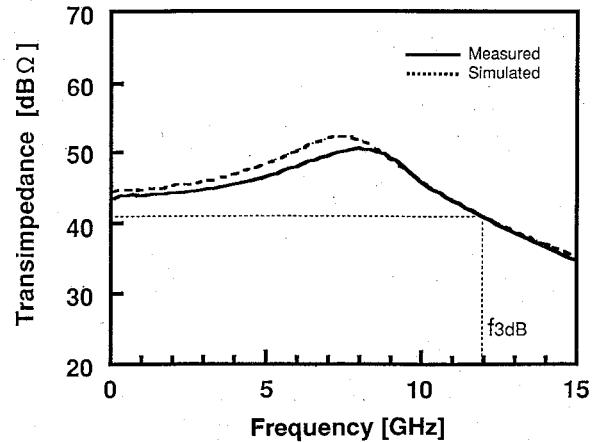


Fig. 7. Transimpedance characteristics of the IC.

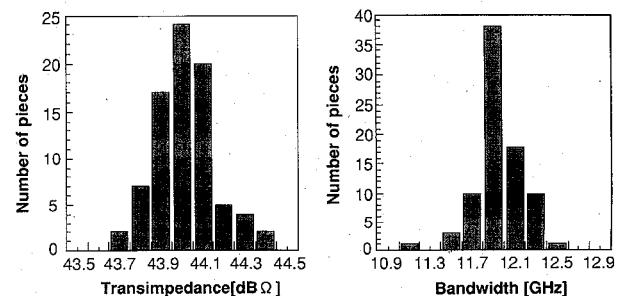


Fig. 8. Distribution of transimpedance and 3 dB bandwidth.

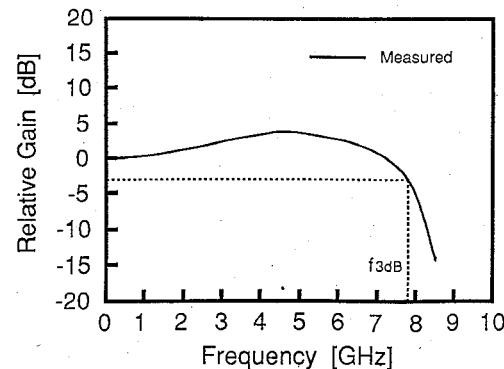


Fig. 9. Frequency response of the receiver.

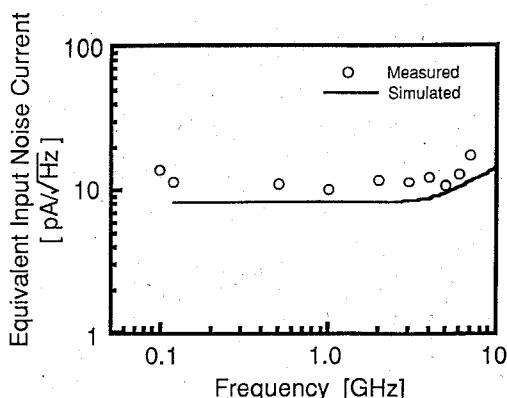


Fig. 10. Equivalent input noise current of the receiver.

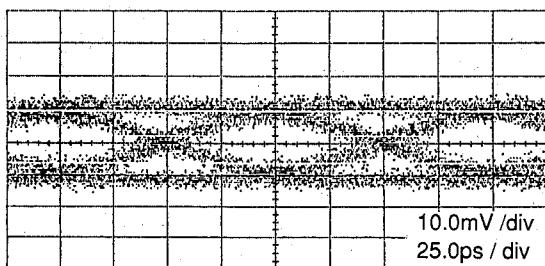


Fig. 11. Pulse response at 10 Gb/s NRZ signals of the receiver.

to 60 nA, the overall capacitance is 0.27 pF, and the 3 dB bandwidth is 15 GHz. To reduce the effect of parasitic capacitance and inductance added between the IC and the photodiode, bare chips are assembled on a ceramic carrier. A 3 dB bandwidth for the receiver of 7.8 GHz has been obtained, which satisfies our design target.

Fig. 10 shows noise performance. The equivalent input noise current \sqrt{in} of approximately $10 \text{ pA}/\sqrt{\text{Hz}}$ has been obtained over the entire frequency range from dc to 7.0 GHz. This indicates superior low noise performance of the IC.

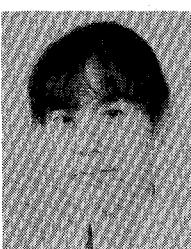
Fig. 11 shows the pulse response at 10 Gb/s NRZ. Output voltage swing of 20 mVp-p corresponds to optical input power of -7.4 dBm . A good open eye pattern has been observed. These results suggest that the preamplifier IC developed in this work is suitable for a 10 Gb/s optical communication system.

CONCLUSION

An ultra broadband preamplifier IC using BPLDD SAGFETs having extremely short gate fingers has been designed and fabricated for a 10 Gb/s optical communication system. The IC shows high transimpedance of $44 \text{ dB}\Omega$ and broad bandwidth of 12 GHz. As a result of optimizing the gate width of the input FET and the feedback resistance, broad bandwidth of 7.8 GHz and an average low equivalent noise current of $12.6 \text{ pA}/\sqrt{\text{Hz}}$ have been obtained for a receiver with this preamplifier IC and a photodiode. The preamplifier IC developed in this work is suitable for a 10 Gb/s optical communication.

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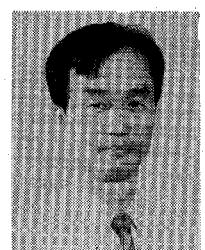
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